

ABSTRACT

It is disclosed a semiconductor wafer position detecting system, a semiconductor device fabricating facility of using the same, and a semiconductor wafer position detecting method to prevent process failure in advance prior to proceeding various processes.

5 The structure includes a chuck plate formed with at least one or more holes at a portion thereof on which a wafer is normally and closely placed; a fluid line connected between a lower portion of each of the holes and a fluid flow means; at least one or more valves provided on the fluid line to control fluid flow in response to an opening/closing control signal; sensing means provided on the fluid line to detect a state of fluid; output
10 means for outputting signals in response to an output control signal; and a controller for selectively applying an opening/closing control signal and an output control signal to the valve and output means, and detecting the position state of wafer by a measurement signal applied from the sensing means.